

電漿後處理對SiO_x奈米線場發射特性之影響 = The effects of plasma treatments on the field emission characteristics of ...

洪達仁、李世鴻

E-mail: 9707390@mail.dyu.edu.tw

摘要

本研究在(100)矽基板上蒸鍍一層鍍薄膜，在溫度(1000 ° C)、氬氣流量500sccm、成長時間2小時的狀況下誘發析出矽原子以成長SiO_x奈米線。本研究針對鍍膜厚度(5nm ~ 25nm)所析出SiO_x奈米線的結構性質和電漿處理過後，電流與電場間的關係來進行研究。從SEM圖中發現，典型 SiO_x奈米線平均管徑與鍍膜厚度之間呈現幾乎線性的關係。由實驗結果可總結出以下的結論，如果將催化劑鍍膜厚度增大，在成核階段會形成尺寸較大及數量較少的催化劑顆粒，而所析出的SiO_x奈米線的直徑也會較大且數量也會較少。由於尖端曲率較小且場發射點較少，因此這些直徑較大且數量較少的SiO_x奈米線的場發射電流也會降低。因此，我們必須盡可能使鍍膜厚度縮小，所析出的SiO_x奈米線才能獲得不錯的場發射特性。研究發現，雖然典型SiO_x奈米線的場發射電流比奈米碳管來得小，但是經過Ar電漿處理後，SiO_x奈米線的屏蔽效應會被有效地降低，且頂端的形貌會有所改變，使得電子容易從尖端射出。而經過 CF₄電漿處理的SiO_x奈米線會產生叢集的現象，因而提高SiO_x奈米線的表面密度，且其表面呈現凹凸不平的狀態而增加其場發射點。因此，SiO_x奈米線經過電漿後處理可以大幅改善其場發射特性，獲得足以與奈米碳管相比擬的場發射特性。這顯示SiO_x奈米線具有作為場發射元件的發展潛力，這與學界普遍的看法並不相同。 關鍵字：SiO_x奈米線、場發射、觸媒、矽 - 鍍合金

關鍵詞：SiO_x奈米線;場發射;觸媒;矽-鍍合金

目錄

封面內頁 簽名頁 授權書	iii	中文摘要	iii
.	iv	英文摘要	v
.	vi	誌謝	vii
.	x	圖目錄	vii
.	x	表目錄	xv
第一章 簡介	1	1.1 奈米材料的歷史與簡介	1
. 1.1.2 奈米材料的特徵	4	1.2.1 表面效應	4
1.2.2 小尺寸效應	5	1.2.3 量子穿隧效應	7
奈米材料的應用	9	1.3.1 場發電子源	12
1.3.2 場發射電子源的特性	13	1.4 研究動機	14
第二章 文獻回顧	15	2.1 氬氣電漿處理文獻	15
. 2.2 氬氣退火處理文獻	21	第三章 理論與研究方法	25
.	25	3.1 電子場發射理論	25
.	28	3.2 奈米線的成長機制	28
3.2.1 Vapor-Liquid-Solid(VLS)	29	3.2.2 氧化輔助生長(Oxide-Assisted Growth, OAG)	31
3.2.3 Vapor-Solid(VS)	33	3.2.4 Solution-Liquid-Solid	34
3.2.5 Solid-Liquid-Solid(SLS)	36	3.2.6 Solid-Solid transformation(SS)	38
3.3 電漿蝕刻機制	39	3.4 實驗儀器原理	40
.	40	3.4.1 熱蒸鍍系統	40
.	41	3.4.2 高溫爐管系統	41
.	45	3.4.3 電漿蝕刻系統	42
.	45	3.4.4 掃描式電子顯微鏡系統	45
的分析	48	3.4.5 能量散佈分析儀系統	46
.	51	3.4.6 FTIR (霍氏轉換紅外光譜儀)	48
.	52	3.4.7 場發射量測裝置系統	49
.	53	3.5 實驗步驟	51
3.5.1 蒸鍍	51	3.5.2 成長SiO _x 奈米線	52
3.5.3 電漿後處理	53	3.5.4 電性量測	53
第四章 實驗結果與討論	54	4.1 典型SiO _x 奈米線的研究與討論	54
.	54	4.1.1 掃描式電子顯微鏡(SEM)的分析	54
.	61	4.1.2 電子場發射分析	61
4.2 Ar電漿後處理對SiO _x 奈米線的的研究與討論	64	4.2.1 掃描式電子顯微鏡(SEM)的分析	64
4.2.2 穿透式電子顯微鏡(TEM)的分析	68	4.2.2 能量散佈分析儀(EDS)的分析	69
4.2.3 能量散佈分析儀(EDS)的分析	69	4.2.4 霍氏轉換紅外光譜儀(FTIR)的分析	71
4.2.4 霍氏轉換紅外光譜儀(FTIR)的分析	71	4.2.5 電子場發射的分析	73
4.3 CF ₄ 電漿後處理對SiO _x 奈米線的研究與討論	77	4.3.1 掃描式電子	

顯微鏡(SEM)的分析	77	4.3.2 穿透式電子顯微鏡(TEM)的分析	80	4.3.3 能量散佈
分析儀(EDS)的分析	81	4.3.4 霍氏轉換紅外光譜儀(FTIR)的分析	84	4.3.5 電子場
發射的分析	86	4.4 不同電漿處理對SiO _x 奈米線的研究與討論	90	4.4.1 掃描式
電子顯微鏡(SEM)的分析比較	90	4.4.2 穿透式電子顯微鏡(TEM)的分析比較	92	4.4.3 能量
散佈分析儀(EDS)的分析比較	93	4.4.4 霍氏轉換紅外光譜儀(FTIR)的分析比較	94	4.4.5 電
流密度的分析比較	96	第五章 結論	98	參考
文獻	101			

參考文獻

- [1] A. S. Edelstein and R. C. Cammarata, Chap. 1 in "Nanomaterials: Synthesis, Properties and Applications", Ed. by A. S. Edelstein and R. C. Cammarata, IOP Publishing. (1996).
- [2] H. W. Kroto, J. R. Heath, S. C. O' Brian, R. F. Curl, & R. E. Smalley, "C₆₀: Buckminsterfullerene", Nature. 318, pp. 162-163. (1985).
- [3] W. Kratschmer, L. D. Lamb, K. Fostiropoulos, & D. R. Huffman, "A new form of carbon. Nature", Solid C60. 347, pp. 354-358. (1990).
- [4] A. Maiti, C. J. Brabec, C. Roland, & J. Bernholc, "Theory of carbon nanotube growth", Phys. Rev. Lett. 52, pp. 14850-14858. (1995).
- [5] 林景崎, "奈米材料導論", (2004)。
- [6] T. C. Cheng, a J. Shieh, W. J. Huang, M. C. Yang, M. H. Cheng, H. M. Lin, and M. N. Chang, App. Phys. Lett. 88, pp. 263118. (2006).
- [7] D. Whang, S. Jin, Y. Wu and C. M. Lieber, "Large-Scale Hierarchical Organization of Nanowire Arrays for Integrated Nanosystems", Nano Lett. 3, pp. 1255-1259. (2003).
- [8] J. Xiang, W. Lu, Y. Hu, Y. Wu, H. Yan, and C. M. Lieber, "Ge/Si nanowire heterostructures as highperformance field-effect transistors", Nature. 441, pp. 498-493. (2006).
- [9] F. C. K. Au, K. W. Wong, Y. H. Tang, Y. F. Zhang, I. Bello and S. T. Lee, "Electron field emission from silicon nanowires", Appl. Phys. Lett. 75, pp. 1700. (1999).
- [10] S. T. Purcell, V. T. Binh and N. Garcia, "64 meV measured energy dispersion from cold field emission nanotips", Appl. Phys. Lett. 67, pp. 436. (1995).
- [11] W. A. Deheer, A. Chatelain and D. Ugarte, "A carbon nanotube field-emission electron source", Science. 270, pp. 1179. (1995).
- [12] Iijima S. "Helical microtubules of graphitic carbon", Nature. 354, pp.56-58. (1991).
- [13] 李元?, 何?, 唐先忠, 等. "納米氧化錫的製程與特性測試", 實驗科學與技術, 1, pp.61-62. (2003)。
- [14] 田時開, 江天府, 楊興華, 曾葆青, "碳納米管薄膜的製程及處理對場發射特性的影響", 電子科技大學學報, 第36卷, 第6期. (2006)。
- [15] N. D. Jonge, Y. Lamy, K. Schoots, et al. "High brightness electron beam from a multi-walled carbon nanotube", Nature. 420, pp. 393-395. (2002).
- [16] 張兆祥, 張耿明, 侯士敏, 等. "碳納米管的薄膜場發射", 真空科學技術學報, 23, pp. 27-32. (2003)。
- [17] W. Zhu, "Vacuum Microelectronics", Wiley, New York. (2001).
- [18] N. S. Xu, and S. Ejaz Huqb, Mater. Sci. Eng. 48, pp. 47. (2005).
- [19] W. A. de Heer, A. Chatelain, and D. Ugarte, Science. 269, pp. 1179. (1995).
- [20] Y. B. Li, Y. Bando, D. Golberg, and K. Kurashima, "Field emission from MoO₃ nanobelts", Appl. Phys. Lett. 81, pp. 5048. (2002).
- [21] Y. Tu, Z. P. Huang, D. Z. Wang, J. G. Wen, and Z. F. Ren, "Growth of aligned carbon nanotubes with controlled site density", Appl. Phys. Lett. 80, pp. 4018. (2002).
- [22] G. Z. Yue, Q. Qiu, B. Gao, Y. Cheng, J. Zhang, H. Shimoda, S. Chang, J. P. Lu, and O. Zhou, "Generation of continuous and pulsed diagnostic imaging x-ray radiation using a carbon-nanotube-based field-emission cathode", Appl. Phys. Lett. 81, pp. 355. (2002).
- [23] C. S. Hsieh, G. Wang, D. S. Tsai, R. S. Chen, and Y. S. Huang, "Field emission characteristics of ruthenium dioxide nanorods", Nanotechnology. 16, pp. 1885-1891. (2005).
- [24] C. K. A. Frederick, K. W. Wong, Y. H. Tang, Y. F. Zhang, I. Bello, and S. T. Lee, "Electron field emission from silicon nanowires", Appl. Phys. Lett. 75, pp. 1700. (1999).
- [25] D. Banerjee, S. H. Jo, and Z. F. Ren, Adv. Mater. Weinheim, Ger. 16, pp. 2028. (2004).
- [26] J. Zhou, L. Gong, S. Z. Deng, J. Chen, J. C. She, N. S. Xu, R. Yang, and Z. Wang, "Growth and field-emission property of tungsten oxide nanotip arrays", Appl. Phys. Lett. 87, pp. 223108. (2005).
- [27] Y. H. Tang, X. H. Sun, F. C. K. Au, L. S. Liao, H. Y. Peng, C. S. Lee, S. T. Lee, and T. K. Sham, "Microstructure and field-emission characteristics of boron-doped Si nanoparticle chains", Appl. Phys. Lett. 79, pp. 1673. (2001).
- [28] M. Lu, M. K. Li, L. B. Kong, X. Y. Guo, and H. L. Li, "Synthesis and characterization of well-aligned quantum silicon nanowires arrays", Composites. 35, pp. 179. (2004).
- [29] A. M. Morales, and C. M. Lieber, "A Laser Ablation Method for the Synthesis of Crystalline Semiconductor Nanowires", Science. 279, pp.

208-211. (1998).

- [30] H. F. Yan, Y. J. Xing, Q. L. Hang, D. P. Yu, Y. P. Wang, J. Xu, Z. H. Xi, and S. Q. Feng, "Growth of amorphous silicon nanowires via a solid-liquid-solid mechanism", *Chem. Phys. Lett.* 323, pp. 224-228. (2000).
- [31] S. T. Lee, Y. F. Zhang, N. Wang, Y. H. Tang, I. Bello, C. S. Lee, and Y. W. Chung, "Semiconductor nanowires from oxides", *Mater. Res.* 14, pp. 4503-4507. (1999).
- [32] Z. L. Wang, R. P. Gao, Z. W. Pan, and Z. R. Dai, "Nano-scale mechanics of nanotubes, nanowires, and nanobelts", *Adv. Eng. Mater.* 3, pp. 657. (2001).
- [33] C. X. Xu, and X. W. Sun, "Field emission from zinc oxide nanopins", *Appl. Phys. Lett.* 83, pp. 3806. (2003).
- [34] J. Niu, J. Sha, X. Ma, J. Xu, and D. Yang, "Array-orderly single crystalline silicon nano-wires", *Chem. Phys. Lett.* 367, pp. 528-532. (2003).
- [35] L. Gangloff, E. Minoux, K. B. K. Teo, P. Vincent, V. T. Semet, V. T. Binh, M. H. Yang, I. Y. Y. Bu, R. G. Lacerda, G. Pirio, J. P. Schnell, D. Pribat, D. G. Hasko, G. A. J. Amaratunga, W. I. Milne, and P. Legagneux, *Nano Lett.* 4, pp. 1575. (2004).
- [36] L. Dvorson, G. Sha, I. Kymissis, C. Y. Hong, and A. Akinwande, "Electrical and optical characterization of field emitter tips with integrated vertically stacked focus", *IEEE Trans. Electron Devices.* 50, pp. 2548-2558. (2003).
- [37] S. Itoh, M. Tanaka, and T. Tonegawa, "Development of field emission displays", *J. Vac. Sci. Technol.* 22, pp. 1362-1366. (2004).
- [38] Y. Cui, and Charles M. Lieber, "Functional nanoscale electronic devices assembled using silicon nanowire building blocks", *Science.* 291, pp. 851-853. (2001).
- [39] Baoqing. Zeng, Guangyong. Xiong, Shuo. Chen, S. H. Jo, W. Z. Wang, D. Z. Wang, and Z. F. Ren, "Field emission of nanowires", *App. Phys. Lett.* 88, pp. 213108. (2006).
- [40] T. C. Cheng, J. Shieh, W. J. Huang, M. C. Yang, M. H. Cheng, "Hydrogen plasma dry etching method for field emission application", *App. Phys. Lett.* 88, pp. 263118. (2006).
- [41] M. J. Yang, J. Shieh, S. L. Hsu, I. J. Huang, C. C. Leu, S. W. Shen, T. Y. Huang, P. Lehnen, and C. H. Chien, "Low-temperature growth of polycrystalline Ge films on SiO₂ substrate by HDPCVD", *Electrochem. Solid-State Lett.* 8, pp. C74. (2005).
- [42] 楊閔智, 謝健, 許瓊姿, 鄭宗杰, "以氫電漿乾式蝕刻法製作準直矽奈米草陣列", *奈米通訊*.第十二卷第三期, pp. 44-49.
- [43] M. C. Yang, J. Shieh, C. C. Hsu, and T. C. Cheng, "Well-aligned silicon nanograss fabricated by hydrogen plasma dry etching", *Electrochem. Solid-State Lett.* 8, pp. C131. (2005).
- [44] R. H. Fowler, and L. Nordheim, *Proc. R. Soc. London.* 119, pp. 137. (1928).
- [45] S. Sadewasser, Th. Glatzel, M. Rusu, A. Jager-Waldau, and M. Ch. Lux-Steiner, "High-resolution work function imaging of single grains of semiconductor surfaces", *Appl. Phys. Lett.* 80, pp. 2979. (2002).
- [46] J. M. Bonard, K. A. Dean, B. F. Coll, and C. Klinke, "Field Emission of Individual Carbon Nanotubes in the Scanning Electron Microscope", *Phys. Rev. Lett.* 89, pp. 197602. (2002).
- [47] J. M. Bonard, K. A. Dean, B. F. Coll, and C. Klinke, *Phys. Rev. Lett.* 89, pp. 197602. (2002).
- [48] M. C. Rossi, S. Salvatori, P. Ascarelli, E. Cappelli, and S. Orlando, "Effect of nanostructure and back contact material on the field emission properties of carbon films", *Diamond Relat. Mater.* 11, pp. 819-823. (2002).
- [49] F. C. K. Au, K. W. Wong, Y. H. Tang, Y. F. Zhang, I. Bello, and S. T. Lee, "Electron field emission from silicon nanowires", *Appl. Phys. Lett.* 75, pp. 1700. (1999).
- [50] C. J. Edgcombe, and U. Valdre', *Philos. Mag.* 82, pp. 987. (2002).
- [51] C. A. Spindt, I. Brodie, L. Humphrey, and E. R. Westerberger, *J. App. Phys. Lett.* 47, pp. 5248. (1976).
- [52] E. Minoux, O. Groening, K. B. J. Teo, S. H. Dalal, L. Gangloff, J. P. Schnell, L. Hudanski, I. Y. Y. Bu, P. Vincent, P. Legagneux, G. A. J. Amaratunga, and W. I. Milne, *Nano Lett.* 5, pp. 2135. (2005).
- [53] C. N. R. Rao, F. L. Deepak, G. Gundiah, and A. Gorindarj, *Prog. Solid State Chem.* 31, pp. 5. (2003).
- [54] R. S. Wagner, and W. C. Ellis, "Vapor-liquid-solid mechanism of single crystal growth", *App. Phys. Lett.* 4, pp. 89. (1964).
- [55] R. S. Wagner, and W. C. Ellis, *Trans. Met. Soc. AIME.* 233, pp. 1053. (1965).
- [56] R. S. Wagner, "Whisker technology", Edited by *App. Phys. Lett.*, Wiley New York. 3, pp. 47-119. (1970).
- [57] Y. Wu and P. Yang, *J. Am. Chem.* "Direct observation of vapor-liquid-solid nanowire growth", *Science.* 123, pp. 3165-3166. (2001).
- [58] Y. W. Wang, C. H. Liang, G. W. Meng, X. S. Peng, and L. D. Zhang, *J. Matter. Chem.* 12, pp. 651. (2002).
- [59] D. P. Yu, Q. L. Hang, Y. Ding, H. Z. Zhang, Z. G. Bai, J. J. Wang, Y. H. Zou, W. Qian, G. C. Xiong, and S. Q. Feng, "Amorphous silica nanowires: Intensive blue light emitters", *Appl. Phys. Lett.* 73, pp. 3076. (1998).
- [60] H. F. Zhang, C. M. Wang, Edgar C. Buck, and L. S. Wang, "Synthesis, characterization, and manipulation of helical SiO₂ Nanosprings", *Nano Lett.* 3, pp. 577-580. (2003).
- [61] X. C. Wu, W. H. Song, K. Y. Wang, T. Hu, B. Zhao, Y. P. Sun, and J. J. Du, "Preparation and photoluminescence properties of amorphous silica nanowires", *Chem. Phys. Lett.* 336, pp. 53. (2001).
- [62] Y. J. Chen, J. B. Li, Y. S. Han, Q. M. Wei, and J. H. Dai, "A novel morphology of SiO_x nanowires with a modified", *App. Phys. Lett.* 74, pp. 433-435. (2002).

- [63] J. C. Wang, C. Z. Zhan, and F. G. Li, "The synthesis of silica nanowire arrays", *Solid State Commun.* 125, pp. 629-631. (2003).
- [64] Z. W. Pan, Z. R. Dai, C. Ma, and Z. L. Wang, *J. Am. Chem. Soc.* 124, pp. 1817. (2002).
- [65] S. H. Sun, G. W. Meng, M. G. Zhang, Y. T. Tian, T. Xie, and L. D. Zhang, *Solid State Commun.* 128, pp. 287. (2003).
- [66] J. Hu, Y. Bando, J. Zhan, X. Yuan, T. Sekiuchi, and D. Golberg, *Adv. Matter.* 17, pp. 971. (2005).
- [67] S. T. Lee, N. Wang, Y. F. Zhang, and Y. H. Tang, "Oxide-assisted semiconductor nanowire growth", *MRS Bull.* 24, pp 36-42. (1999).
- [68] S. T. Lee, Y. F. Zhang, N. Wang, Y. H. Tang, I. Bello, C. S. Lee, and Y. W. Chung, and Y. W. Chung, *J. Mater. Res.* 14, pp. 4503. (1999).
- [69] N. Wang, Y. H. Tang, Y. F. Zhang, C. S. Lee, and S. T. Lee, *Phys. Rev.* 58, pp. R16024. (1998).
- [70] T. S. Chu, R. Q. Zhang, and H. F. Cheung, "Geometric and electronic structures of silicon oxide clusters" *J. Phys. Chem.* 105, pp. 1705-1709. (2001).
- [71] R. Q. Zhang, Y. Lifshitz, and S. T. Lee, *Adv. Matter.* 15, pp. 635. (2003).
- [72] X. M. Meng, J. Q. Hu, Y. Jiang, C. S. Lee, and S. T. Lee, "Oxide-assisted growth and characterization of Ge/SiO_x nanocables", *App. Phys. Lett.* 83, pp. 2241. (2003).
- [73] Y. Cui, L. J. Lauhon, M. S. Gudiksen, J. F. Wang, C. M. Lieber, "Diameter-controlled synthesis of single-crystal silicon nanowires", *App. Phys. Lett.* 78, pp. 2214. (2001).
- [74] G. W. Zhou, H. Li, H. P. Sun, D. P. Yu, Y. Q. Wang, X. J. Huang, L. Q. Chen, and Z. Zhang, *App. Phys. Lett.* 75, pp. 2447. (1999).
- [75] D. D. D. Ma, C. S. Lee, F. C. K. Au, S. Y. Tong, S. T. Lee, "Small-diameter silicon nanowire surfaces", *Science.* 299, pp. 1874. (2003).
- [76] Y. F. Zhang, Y. H. Tang, N. Wang, C. S. Lee, I. Bello, and S. T. Lee, "Germanium nanowires sheathed with an oxide layer", *Phys. Rev.* 61, pp. 4518-4521. (2000).
- [77] W. S. Shi, Y. F. Zheng, N. Wang, C. S. Lee, and S. T. Lee, "Microstructures of gallium nitride nanowires synthesized by oxide-assisted method", *Chem. Phys. Lett.* 345, pp. 377-380. (2001).
- [78] H. Y. Peng, X. T. Zhou, N. Wang, Y. F. Zheng, L. S. Liao, W. S. Shi, C. S. Lee, and S. T. Lee, *Chem. Phys. Lett.* 327, pp. 263. (2000).
- [79] W. S. Shi, Y. F. Zheng, N. Wang, C. S. Lee, and S. T. Lee, *Adv. Matter.* 13, pp. 591. (2001).
- [80] W. S. Shi, Y. F. Zheng, N. Wang, C. S. Lee, and S. T. Lee, "Oxide-assisted growth and optical characterization of gallium-arsenide nanowires", *App. Phys. Lett.* 78, pp. 3304. (2001).
- [81] W. S. Shi, Y. F. Zheng, N. Wang, C. S. Lee, and S. T. Lee, *J. Vac. Sci. Technol.* 19, pp. 1115. (2001).
- [82] J. Q. Hu, X. L. Ma, Z. Y. Xie, N. B. Wong, C. S. Lee, I. Bello, and S. T. Lee, *Chem. Phys. Lett.* 344, pp. 97. (2001).
- [83] Y. H. Tang, N. Wang, Y. F. Zhang, C. S. Lee, I. Bello, and S. T. Lee, "Synthesis and characterization of amorphous carbon nanowires", *Appl. Phys. Lett.* 75, pp. 2921. (1999).
- [84] K. H. Lee, S. W. Lee, R. R. Vanflee, and W. Sigmund, *Chem. Phys. Lett.* 376, pp. 498. (2003).
- [85] Y. Zhang, N. Wang, R. He, J. Liu, X. Zhang, and J. Zhu, "A simple method to synthesize Si₃N₄ and SiO₂ nanowires from Si or Si/SiO₂ mixture", *J. Cryst. Growth.* 233, pp. 803-808. (2001).
- [86] L. Dai, X. L. Chen, T. Zhou, and B. Q. Hu, "Aligned silica nanofibres", *J. Phys.:Condens. Matter.* 14, pp. L473. (2002).
- [87] L. Dai, X. L. Chen, J. K. Jian, W. J. Wang, T. Zhou, and B. Q. Hu, "Strong blue photoluminescence from aligned silica nanofibers", *Appl. Phys. Lett.* 76, pp. 625-627. (2003).
- [88] T. J. Trentler, K. M. Hickman, S. C. Goel, Ann M. Viano, Patrick C. Gibbons, and W. E. Buhro, "Solution-liquid-solid growth of crystalline III-V semiconductors: An analogy to vapor-liquid-solid growth", *Science.* 270, pp. 1791-1974. (1995).
- [89] X. Lu, T. Hanrath, K. P. Johnston, and B. A. Korgel, "Growth of single crystal silicon nanowires in supercritical solution from tethered gold particles on a silicon substrate", *Nano Lett.* 3, pp. 93-99. (2003).
- [90] Y. J. Xing, Z. H. Xi, Z. Q. Xue, and D. P. Yu, *Chin. Phys. Lett.* 20, pp. 700. (2003).
- [91] Y. J. Xing, Z. H. Xi, D. P. Yu, Q. L. Hang, H. F. Yan, S. Q. Feng, and Z. Q. Xue, "Growth of silicon nanowires by heating Si substrate", *Chin. Phys. Lett.* 19, pp. 240. (2002).
- [92] S. H. Sun, G. W. Meng, T. Gao, M. G. Zhang, Y. T. Tian, X. S. Peng, Y. X. Jin and L. D. Zhang, "Micrometer-sized Si-Sn-O structures With SiO_x nanowires on their surface", *Appl. Phys. Lett.* 76, pp. 999-1002. (2003).
- [93] B. T. Park, and K. Yong, "Controlled growth of core-shell Si-SiO_x and amorphous SiO₂ nanowires directly from NiO/Si", *Nanotechnology.* 15, pp. S365-370. (2004).
- [94] M. Paulose, O. K. Varghese, and C. A. Grimes, *J. Nanosci. Nanotech.* 3, pp. 341. (2003).
- [95] K. H. Lee, H. S. Yang, K. H. Baik, J. Bang, R. R. Vanfleet, and W. Sigmund, "Direct growth of amorphous silica nanowires by solid state transformation of SiO₂ films", *Chem. Phys. Lett.* 383, pp. 380. (2004).
- [96] H. Hanamura, H. Itoh, Y. Shimogaki, J. Aoyama, T. Yoshimi, J. Ueda, and H. Komiyama, *Thin Solid Films.* 320, pp. 31. (1998).
- [97] Lieberman, M. A., and A. J. Lichtenberg, "Principles of Plasma Discharges and Materials Processing", John Wiley & Sons Inc. (1994).
- [98] H. Xiao, "Introduction to Semiconductor Manufacturing Technology", Prentice Hall Inc. (2001).
- [99] 李世鴻著, 積體電路製程技術, 五南圖書出版公司印行, (1998).
- [100] C. H. Liang, G. W. Meng, L. D. Zhang, Y. C. Wu, Z. Cui, "Large-scale synthesis of -SiC nanowires by using mesoporous silica

embedded with Fe nanoparticles ” , Chem Phys Lett. 329, pp. 323-328. (2000).

[101] D. C. Bell, Y. Wu, C. J. Barrelet, S. Gradecak, J. Xiang, B. P. Timko, and C. M. Lieber, *Microse. Res. Tech.* 64, pp. 373. (2004).

[102] H. Takikawa, M. Yatsuki, and T. Sakakibara, “ Synthesis of silicon oxide nanofibers by sublimation of SiC in medium vacuum with oxygen flow ” , *Jpn. J. Appl. Phys.* 38, pp. L401. (1999).

[103] Y. W. Zhu, F. C. Cheong , T. Yu, X. J. Xu, C. T. Lim, J. T. L. Thong, Z. X. Shen, C. K. Ong, Y. J. Liu, A. T. S. Wee, C. H. Sow, “ Effects of CF₄ plasma on the field emission properties of aligned multi-wall carbon nanotube films ” , *Carbon.* 43, pp. 395-400. (2005).

[104] 許博凱著，奈米碳管電漿後處理對場發射特性之影響 ” ，大葉大學碩士論文，(2007)。

[105] Y. L. Chueh, L. J. Chou, S. L. Cheng, J. H. He, W. W. Wu, and L. J. Chen, “ Synthesis of taperlike Si nanowires with strong field emission ” , *App. Phys. Lett.* 86, pp. 133112. (2005).